

ABSTRACT

A method of calibrating a crossconnect including a MEMS device and another optical device, each of which further include a plurality of elements, the method including determining a relationship between an applied voltage and an angle response for a number of the elements of the MEMS device, determining a function of beam position and element position for the number of the elements of the MEMS device, assembling the MEMS device and the another optical device to produce the crossconnect, applying voltages to make sample connections between the MEMS device and the another optical device based on the relationship and the function, determining a transformation for the sample connections caused by packaging the crossconnect, and redetermining the relationship and the function based on the transformation. The method may be iterated more than once to achieve a more accurate determination.